IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No	
Priority Filing Date	July 13, 2001
Inventor	
Assignee	Micron Technology, Inc.
Priority Group Art Unit	1762
Priority Examiner	Eric B. Fuller
Attorney's Docket No	MI22-2501
Customer No	021567
Title: Chemical Vapor Deposition Methods of Forming a Barium Strontium	
Titanate Comprising Dielectric Layer Having a Varied Concentration of	
Barium and Strontium Within the Layer	

PRELIMINARY AMENDMENT

To: Mail Stop Patent Application

Commissioner for Patents

P. O. Box 1450

Alexandria, VA 22313-1450

VIA EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)

Wells St. John P.S.

601 West First Avenue, Suite 1300

Spokane, WA 99201-3828

Please enter the following amendments prior to examining the aboveidentified application.

AMENDMENTS